Wyko NT1100 Optical Profiling System

Quantitative 3D Topography for Research and Low-Volume Production



1 Euro coin

The Wyko[®] NT1100 provides accurate, non-contact surface metrology for applications in MEMS, thick films, optics, ceramics, advanced materials and many more.

- Accurate surface topography in a small footprint
- Sub-nanometer vertical resolution at all magnifications
- Motorized stage for stitching large area measurements
- Complete system including Wyko Vision® analysis software





Fast and repeatable, the NT1100 utilizes white light interferometry for high-resolution 3D surface measurements, from sub-nanometer roughness to millimeter-high steps. On super-smooth or rough surfaces, the versatile NT1100 provides repeatable surface measurement for R&D, wear and failure analysis, and process control.

The cost-effective NT1100 offers all the advantages of industry-standard Wyko optical profiling, including the full Wyko Vision[®] analytical software package. Vision, the industry's most comprehensive analysis program, provides over 200 tools to quantify and visualize surface data – all standard.

The NT1100 has the performance features of larger NT Series instruments: easy measurement setup, fast acquisition, comprehensive analysis and Angstrom-level repeatability. The Data Stitching option adds a motorized stage and support software to rapidly scan large surface areas.



Call 520.741.1044 or 1.888.24.VEECO Fax: 520.294.1799 • www.veeco.com

2650 E. Elvira Road • Tucson, AZ 85706 USA

 $^1\mbox{As}$ demonstrated by a PSI measurement with nulled fringes on a SiC reference mirror.

 ^{2}As demonstrated by taking the one sigma Rq value of 30 PSI repeatability measurements on a SiC reference mirror.

U.S. Patents: 4,931,630; 5,133,601; 5,204,734; 5,122,648; 5,335,221; 5,471,303; 5,446,547. Celeron is a registered trademark of Intel Corporation. Microsoft and Windows XP are registered trademarks of Microsoft Corporation. Wyko and Vision are registered trademarks of Vecco Instruments Inc. Specifications are subject to change without notice. Copyright © 2006 Vecco Instruments Inc. DS501, Rev A5

Specifications

SYSTEM Measurement Techniques

Measurement Capability

Objectives

Field-of-View Lenses Measurement Array Light Source

Stages

Optical Assembly

Video Display Computer System

Software

PERFORMANCE

Vertical Measurement Range Vertical Resolution¹ RMS Repeatability² Vertical Scan Speed Lateral Spatial Sampling Field-of-View

Reflectivity

ENVIRONMENT

Temperature Range Humidity Range Vibration

DIMENSIONS

Microscope

WEIGHT

Microscope Shipping Weight

POWER REQUIREMENTS

Input Voltage

Power Consumption Compressed Air optical phase-shifting and white light vertical scanning interferometry

three-dimensional, non-contact, surface profile measurements

1.5X, 2.5X, 5.0X, 10X, 20X, 50X; long working distance objectives available; optional manual turret

0.5X, 0.75X, 1.0X, 1.5X, 2.0X

user-selectable, maximum array 736 x 480

tungsten halogen lamp (user-replaceable); manual filter selection

manual; ± 50.8mm (± 2 in.) X/Y translation, ± 4° tip/tilt; optional automated stitching stage, ± 50.8mm (2 in.) X/Y

integrated illuminator; interchangeable discrete field-of-view lenses; closed-loop precision vertical scanning assembly

127mm (5 in.) monochrome monitor

PC with latest Celeron® processor, 430mm (17 in.) SVGA monitor; optional printers and network cards

Wyko Vision[®] software running under Microsoft[®] Windows XP[®]

0.1nm to 1mm < 1Å Ra 0.01nm up to 7.2µm/sec (288µin./sec) 0.08 to 13.1µm 8.24mm to 0.05mm (larger areas with Data Stitching option) 1% to 100%

between 15 and 30 °C (59 to 86 °F) ≤ 80%, non-condensing optional isolation system (recommended)

399mm W x 508mm D x 737mm H (15.5in. W x 20in. D x 29in. H)

does not exceed 56.7 kg (125 lbs) 204.1 kg (450 lbs)

user-selectable 100–120 VAC/200–240 VAC, 50–60 Hz < 300 W 4.2–7.0 kg/cm (60–100 PSI) for optional isolation system